

INFORMATION DISCLOSURE STATEMENT

Applicant	:	Satoh <i>et al.</i>
App. No.	:	10/759,953
Filed	:	January 16, 2004
For	:	SEMICONDUCTOR-PROCESSING DEVICE PROVIDED WITH A REMOTE PLASMA SOURCE FOR SELF-CLEANING
Examiner	:	Jeffrie Robert Lund
Art Unit	:	1792
Conf No.	:	8185

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:


Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 1 reference to be considered by the Examiner.

Please place this reference in the file of the above-identified patent application in accordance with 37 C.F.R. § 1.97(i).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 8/17/09

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